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Karpuzov, D.S., M.G. Kalitzova, G. Vitali, S. Kostic, D.G. Armour and G. Carter, Radiation damage in Ge induced by $Te^+$ implantation near channeling conditions . . . . . B39 (1989) 417
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Kato, M., M. Katayama, T. Chassé and M. Aono, Channeling and backscattering of low energy ions . . . . . B39 (1989) 30
Kawabe, M., Y. Ikeda, K. Ogawa, T. Shiraishi, S. Yokoyama, Y. Nanichi and Y. Bando, Lateral control of impurity-induced disordering of AlAs/GaAs superlattice . . . . . B39 (1989) 441
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Kelly, R., Bombardment-induced compositional change with alloys, oxides, oxysalts and halides. II. The role of segregation . . . . . B39 (1989) 43
Kenny, M.J., J.T.A. Pollock and L.S. Wielunski, Ion-implanted graphitic carbons . . . . . B39 (1989) 704
Khriaschev, G.S., see Gerasimenko, N.N. . . . . B39 (1989) 480
Kikuchi, A., H. Naramoto, K. Ozawa and Y. Kazumata, Damage profiles in alkali halides irradiated with high-energy heavy ions . . . . . B39 (1989) 724
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Kilner, J.A., R.J. Chater, K.J. Reeson, P.L.F. Hemment and J.R. Davis, Nitrogen-15 isotope tracer studies of buried nitride layer formation by high dose implantation . . . . . B39 (1989) 225
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Kinomura, A., M. Takai, T. Matsuo, S. Ujiie, S. Namba, M. Satou, M. Kiuchi, K. Fujii and T. Shiokawa, RBS analysis of beam-processed microarea by focused MeV ion beam ... B39 (1989) 40
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Klaumünzer, S., Li Changlin, S. Löffler, M. Rammensee and G. Schumacher, Plastic flow of vitreous silica and pyrex during bombardment with fast heavy ions ... B39 (1989) 665
Kluge, A., K. Langguth, R. Öchsner, K. Kobs and H. Ryssel, A comparison of the wear behavior of Ag, B, C, N, Pb and Sn implanted steels with 1.5% to 18% chromium ... B39 (1989) 531
Knuyt, G., M. D'Olieslaeger, L. De Schepper and L.M. Stals, Simulation of the growth of inert gas bubbles near the surface of an amorphous alloy ... B39 (1989) 60
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La Ferla, A., F. Priolo, C. Spinella, E. Rimini, F. Baroetto and G. Ferla, Ion-beam-induced expitaxial crystallization of implanted and chemical vapor deposited amorphous silicon ... B39 (1989) 311
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Marletta, G., S. Pignataro and C. Oliveri, Reflection electron energy loss spectroscopy (REELS) of conductive polymers obtained by keV bombardment ... B39 (1989) 773
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Meyer, O., B. Egner, G.C. Xiong, X.X. Xi, G. Linker and J. Geerk, Ion beam modification and analysis of single crystalline $YBa_2Cu_3O_7$ thin films ... B39 (1989) 628

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Miyamoto, I., S.T. Davies and K. Kawata, Sharpening diamond tools having an apex angle of less than 60° with a low energy ion beam . . . B39 (1989) 696
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Momose, Y., M. Noguchi and S. Okazaki, Ar, $O_2$ and $CF_4$ plasma treatment of poly-(vinylidene fluoride), polyimide and polyamidoimide and its relationship to wettability . . . B39 (1989) 805
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Nagayama, T., K. Noguchi, S. Sasaki and R. Shimizu, Ejection pattern of sputtered atoms from Cu(100) under 10 keV $Ar^+$ ion bombardment . . . B39 (1989) 91
Nakagawa, Y., T. Ariyoshi, H. Hanjo, S. Tsutsumi, Y. Fujii, M. Itami, A. Okamoto, S. Ogawa, T. Hamada and F. Fukumaru, Modification of solid surface by intense pulsed light-ion and metal-ion beams . . . B39 (1989) 603
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Nomura, I., T. Miyazaki and T. Nishimura, Novel method in rf bias sputtering . . . B39 (1989) 99
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Nunogaki, M., H. Suezawa, Y. Kuratomi and K. Miyazaki, Effects of preparative ion implantation for application in plasma source nitriding of metals . . . B39 (1989) 591

Obara, K., S.-I. Saito and T. Ogushi, Formation of metastable niobium oxide by the vapor quenching of sputtered particles ... B39 (1989) 652
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Ohmura, Y., M. Iwaki, T. Shiokawa, K. Toyoda, S. Namba and Y. Okabe, A comparative study of D and H implantation-induced shallow donors in Si ... B39 (1989) 377
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